

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Satoshi Watanabe Serial No.: 10/052,687

Serial No.: 10/052,687 Group Art Unit: 1752
Filed: January 18, 2002 Examiner: Thornton, Yvette C.

For: RESIST MATERIAL AND PATTERN FORMING METHOD

Date: December 9, 2003

Confirmation No.: 3765

Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## **REMARKS TO OFFICE ACTION**

Sir:

These remarks are responsive to the Office Action ("Action") dated September 10, 2003 and are filed before expiration of the three month shortened statutory period. Applicants provide the present remarks to address the issues raised in the Action pursuant to the rules stated in revised 37 C.F.R. 1.121 that became effective on July 30, 2003.